

Micro-Scale Oven-Control Advantages

Macro-Scale
 Macro-Oven (containing heater and T sensor)
 Atomic Cell @ 80°C
 3 cm
 Insulation
 Laser
 Thermally Isolating Feet
 $R_{th} = 38 \text{ K/W}$
 $C_{th} = 22 \text{ J/K}$
 $P (@ 80^\circ\text{C}) = 1.5 \text{ W}$
 Warm Up, $\tau = 16 \text{ min.}$

Micro-Scale
 300x300x300 μm^3 Atomic Cell @ 80°C
 Heater
 Laser
 T Sensor (underneath)
 Long, Thin Polysilicon Tethers
 $R_{th} = 83,000 \text{ K/W}$
 $C_{th} = 6.3 \times 10^{-6} \text{ J/K}$
 $P (@ 80^\circ\text{C}) = 2.6 \text{ mW}$
 Warm Up, $\tau = 0.1 \text{ s}$

Thermal Circuit:
 $T = P \times R_{th}$
 $R_{th} \sim \frac{\text{support length}}{\text{X-section area}}$
 $C_{th} \sim \text{volume}$

Advantages:
 550x lower power
 7,300x faster warm up

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Physics Package Power Diss. < 10 mW

Achieved via MEMS-based thermal isolation

Only ~5 mW heating power needed to achieve 80°C cell temperature

Power [mW] vs Temperature [°C] graph:
 Measured (blue diamonds) vs Model (red line).
 Data points: (40, 1), (50, 2), (60, 3), (70, 4), (80, 5), (90, 6), (100, 7), (110, 8), (120, 9), (130, 10), (140, 11).

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Micro Gas Analyzers (MGA)

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Micro Gas Analyzers

- Objective:** enable remote detection of chemical agents via tiny, ultra-low power, fast, chip-scale gas analyzers that greatly reduce the incidence of false positives
- Approach:** use micromachining technologies to implement separation-based analyzers (e.g., gas chromatographs, mass spectrometers) at the micro-scale to enhance gas selectivity

Conventional Sensor:
 Capacitor Plates, Gas Sensitive Polymer
 Species A and B both cause $\Delta C \sim \text{gas conc.}$

Separation Analyzer:
 Species A and B are separated and analyzed individually.

Result: species A & B now separated \Rightarrow can identify and analyze individually

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Advantages of Miniaturization

Portable Gas Chromatograph

19" x 13" x 10" Depth

Chip-Scale Gas Chromatograph

1-2 cm x 5 mm

Reduction Factors

Size	40,500 cm ³	20,000X	Size	2 cm ³
Sensitivity	1 ppb	1,000X	Sensitivity	1 ppt
Analysis Time	15 min.	225X	Analysis Time	4 sec
Energy Per Analysis	10,000 J	10,000X	Energy Per Analysis	1 J

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Basic Approach: Separation Analyzer

Miniaturization

Tiny Dimensions

- > fast time constants
- > 10,000X gain factor via multi-staging
- > enhanced sensitivity
- > lower power

Tiny Dimensions

- > faster separation
- > lower power

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Scaling Leads to Faster Separation

- **Example:** gas chromatograph separation column
 - ↳ unique analyte interactions with the column walls
 - ↳ different analyte velocities
 - ↳ **result:** separation after a finite distance

Stationary Phase

Wide Channel

Thin Channel

Miniaturize

Carrier Gas (Mobile Phase) Peak Broadens

Conc.

Conc.

Peak Stays Thin ⇒ Less Separation Needed to Resolve

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Stationary Phase

Wide Channel

Thin Channel

Miniaturize

Carrier Gas (Mobile Phase)

Column Width ↓

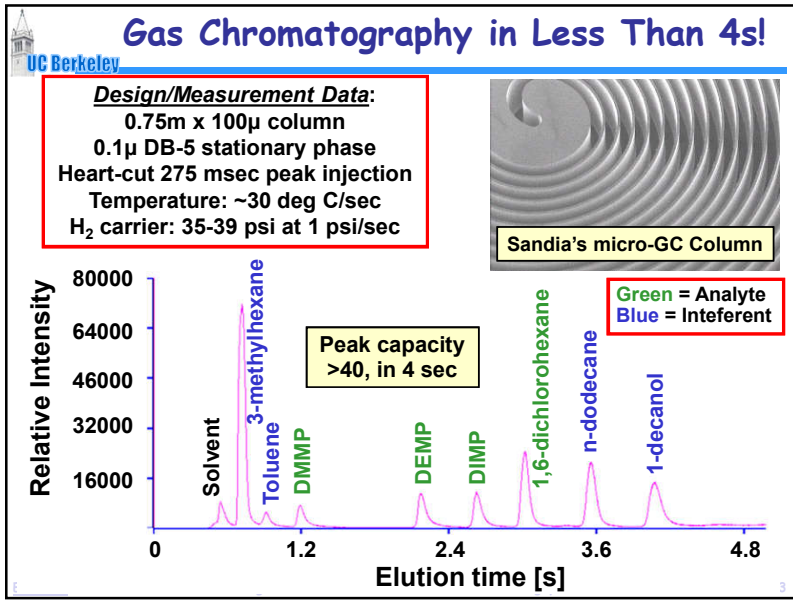
Surface-to-Volume Ratio ↑

Peak Spreading ↓

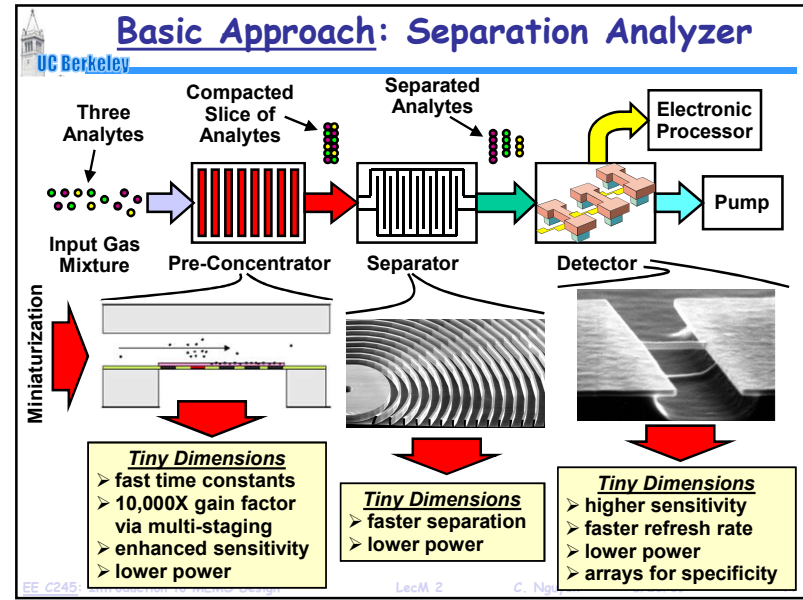
Separation Distance ↓

• **Result of Scaling:** shorter column length; faster analysis time

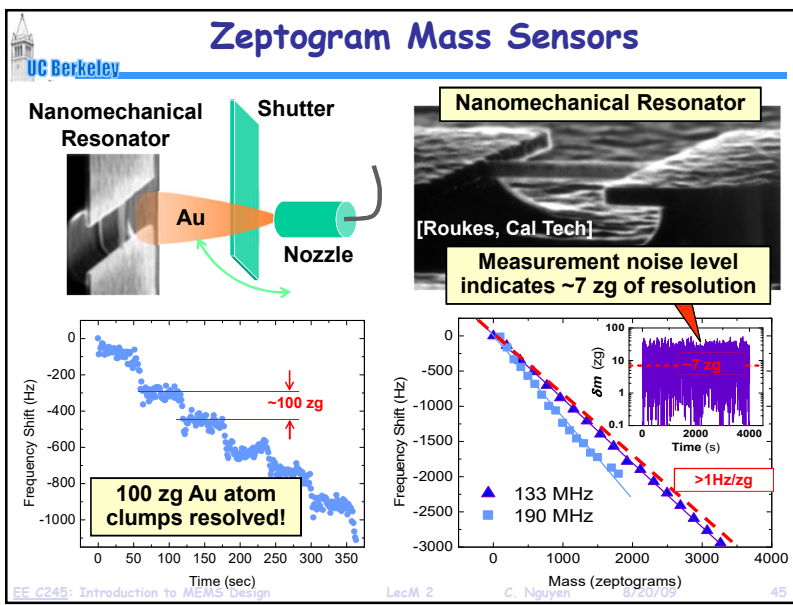
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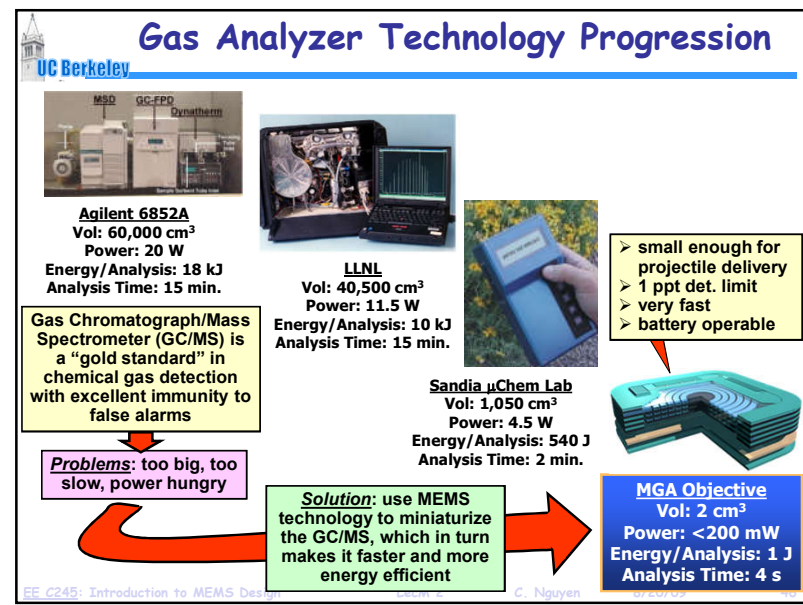
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Example: Micromechanical Accelerometer

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- The MEMS Advantage:**
 - >30X size reduction
 - accelerometer mechanical
 - allows integration with

Tiny mass means small output ⇒ need integrated transistor circuits to compensate

Basic Operation Principle

$x \propto F_i = ma$

Displacement
Spring
Inertial Force
Proof Mass
Acceleration

400 μm
ANALOG DEVICES
100um
12 3091 94
Analog Devices ADXL 78

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Messages Going Forward ...

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- MEMS are micro-scale or smaller devices/systems that operate mainly via a mechanical or electromechanical means
- MEMS ⇒ NEMS offer the same scaling advantages that IC technology offers (e.g., speed, low power, complexity, cost), but they do so for domains beyond electronics:
 - resonant frequency ↑ (faster speed)
 - actuation force ↓ (lower power)
 - # mechanical elements ↑ (higher complexity)
 - integration level ↑ (lower cost)

Size ↓ →

- Micro ... nano ... it's all good
- Just as important: MEMS or NEMS have brought together people from diverse disciplines ⇒ this is the key to growth!
- What's next? ⇒ Nano-nuclear fusion? Chip-scale atomic sensors?

... limitless possibilities ...

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